**User Information**

**Name** *

**Email** *

**Registration Status** * I have completed the new user registration and turned in the appropriate forms to the UH Nanofabrication Facility’s Administrator.

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**Training Request**

**Type**  
- None
- Facility Orientation
- Atomic Force Microscope
- Desktop Sputtering System
- eBeam Evaporator
- eBeam Writer
- Ellipsometer
- Focused Ion Beam (FIB)
- HF Training
- Ion Mill
- Mask
- Aligner
- Nanofab Inventory
- Nanoimprinter
- Optical Microscopes
- Profilometer
- Rapid Thermal Processer
- Reactive Ion Etcher (RIE 100)
- Reactive Ion Etcher (RIE 180)
- Reactive Ion Etcher (RIE 80)
- Scanning Electron Microscope
- Spin Coater
- UHV Sputtering System
- Vacuum Ovens

**Trainer: Dr. Long Chang**
Training Duration: 0.5 hr

**Trainer: Dr. Long Chang**
Training Duration: 2 hrs
Information: You may bring your sample for the training.

**Trainer: Dr. Jing Guo**
Training Duration: 0.5 hrs

**Trainer: Dr. Jing Guo**
Training Duration: 2 hrs
Information: Please specify the material you wish to evaporate in the comment box below.

**Trainer: Dr. Long Chang**
Training Duration: 2 hrs
Information: Trainees are required to use the equipment within two weeks of training. Please describe your substrate/sample and the patterns you wish to print in the comment box below.